

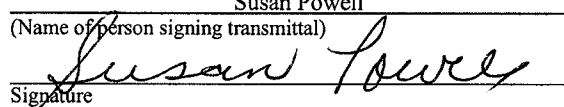
**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant(s) : Koichiro KISHIMA et al.  
Serial No. : 10/540,720  
Filed : January 13, 2006  
For : METHOD FOR MANUFACTURING SEMICONDUCTOR  
SUBSTRATE AND SEMICONDUCTOR SUBSTRATE  
Art Unit : 2818  
Confirmation No. : 2419  
Examiner : David Nhu

745 Fifth Avenue  
New York, New York 10151

**CERTIFICATE OF ELECTRONIC FILING**

I hereby certify that this correspondence is being transmitted via  
Electronic Filing Services on December 14, 2007.

Susan Powell  
(Name of person signing transmittal)  
  
Signature  
December 14, 2007  
Date of Signature

**AMENDMENT UNDER 37 CFR 1.111**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the non-final Office Action mailed October 11, 2007, having a  
shortened term of reply ending on January 11, 2008, please amend the above-identified  
application as follows: